Ultra High Resolution FE SEM

JSM-7500F/JSM-7500FA

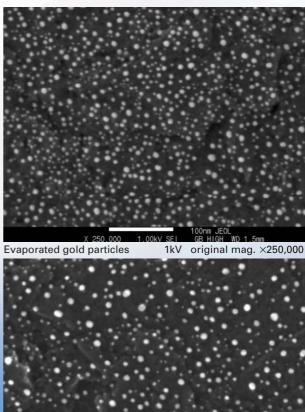
Field Emission SEM/Analytical Field Emission SEM





Ultra High Resolution, Advanced GU





- Ultra high resolution FE SEM with simple operation. You do not have to worry about your skill level.
- Further simplified observation of insulating materials.
 (GB-mode, r-filter)
- Seamless integration for efficient observation and analysis.

(New GUI)

 Integrates the SEM main console and EDS.

(JSM-7500FA)

Five-axis motor controlled stage is standard

(Trackball control).

 Dry vacuum system for clean specimen environment.

(Liquid Nitrogen Trap, TMP)

 Eco friendly (Friendly to environment with the Eco mode)



I -For Efficient Observation & Analysis-

The maximum magnification of $\times 1,000,000$ reveals nano structures

X 500,000 5,0kV sel sem 5kV original mag.×500,000

JSM-7500F

The JSM-7500F is an ultra high resolution FE SEM equipped with a high brightness conical FE gun and a low aberration conical objective lens (semi in-lens).

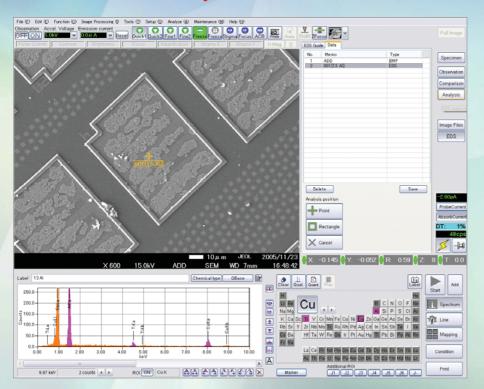
The improved overall stability of the JSM-7500F enables you to readily observe your specimen at magnifications up to ×1,000,000 with the guaranteed resolution of 1 nm.

The energy filter (r-filter) makes it possible to observe the fine surface morphology of nano structures.

10nm JEOL 0kV SEI SEM 5kV original mag.×1,000,000

EDS embedded Analytical FE SEM

Pt catalyst on carbon



JSM-7500FA

The JEOL EDS is embedded in the JSM-7500FA. The JSM-7500FA allows a quick start of elemental analysis on the SEM image, when the elemental analysis and the observation of composition contrast are required, in addition to the observation of fine surface structures. The analysis data are stored automatically with the SEM image, showing the analysis locations in the same folder.

Sophisticated integration of SEM with EDS results from JEOL's many years of experience as a leading maker of Scanning Electron Microscopes and Energy Dispersive X-ray Spectrometers.

Easier Observation of Insulating Materials

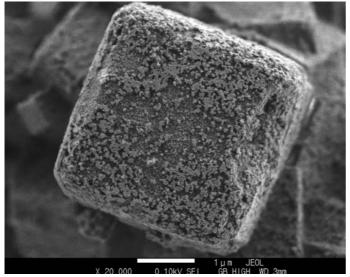
Gentle Beam Mode

The Gentle Beam (GB) method decelerates incident electrons just before they hit the specimen to reduce the incident-electron penetration and the charging in the specimen to observe its top surface.

At the extremely low accelerating voltages between 100 V and 3 kV, the Gentle Beam produces high resolution comparable to that attainable at higher accelerating voltages. Thus, this method is suitable for observation of fine structures, especially on low-density materials.

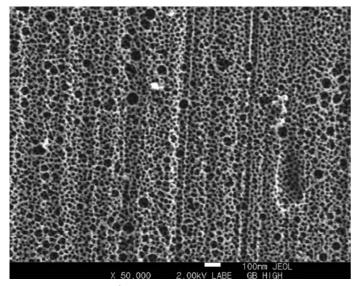
The GB mode can be used for observation of non-conductive materials at high magnification with effective detection of low angle backscattered electrons.

Application of Gentle Beam



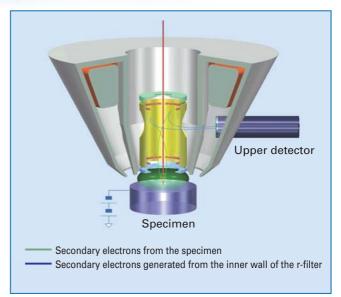
Glass (no coating)

0.1kV original mag. ×20,000

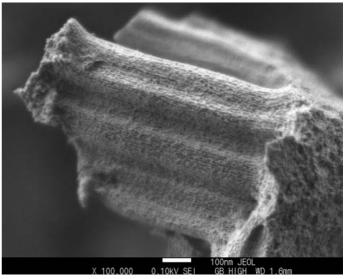


Aluminum oxide (Al₂O₃) (no coating)

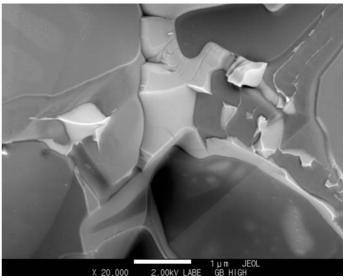
2kV original mag. ×50,000



The Gentle Beam decelerates incident electrons just before the specimen. The secondary electrons from the specimen are accelerated and hit the wall of the new r-filter and generate secondary electrons.



Mesoporous silica (no coating) 0.1kV original mag. ×100,000 Specimen courtesy: Associate Professor Kazuki Nakanishi, Division of Chemistry, Graduate School of Science, Kyoto University.



Ceramic (no coating)

2kV original mag. ×20,000

New r-Filter (Energy filter)

New r-filter

The new r-filter is a unique energy filter composed of the secondary electron control electrode, the backscattered electron control electrode, and the filtering electrodes. The specimen generates electrons with a variety of energies when it is bombarded with incident electrons. The combination of multiple static fields of the new r-filter built into the JSM-7500F lets you freely select secondary electrons and backscattered electrons while keeping the incident electrons on the center of the electron optics.

Optimum filtering with one click

The new r-filter is operated with the easy-tounderstand menu window.

The Sb mode detects secondary electrons with variable mixture of backscattered electrons. The Bs mode detects backscattered electrons with variable mixture of secondary electrons. The mixing ratio can be freely adjusted. Standard button sets the mixing rate to minimum.



Information selected by the new-filter

Standard Sb mode (Detection of secondary electrons) The Standard Sb mode detects pure secondary electrons and is suitable for observation of fine surface morphologies enhanced by the edge effect.

Figure (1): You can clearly observe the surface morphologies on the tungsten and aluminum layers.

Standard Bs mode (Detection of backscattered electrons)

The Standard Bs mode mainly detects the backscattered electrons, which shows the contrast of the com-

Figure (2): The layer of tungsten, which is of higher atomic number, appears white. The layer of aluminum, which is of lower atomic number, appears darker with less contrast of the surface morphology. The contrast of composition variation is enhanced.

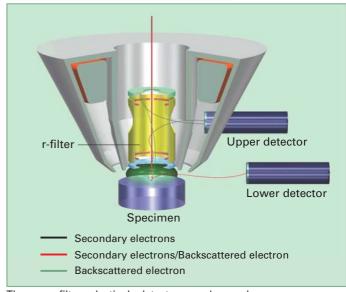
Sb mode (Mainly Secondary electrons)

The Sb mode detects the secondary electrons mixed with a variable fraction of the backscattered electrons. Figure (3): The grain boundaries appear clearer than in the SE mode image due to the composition contrast mixed with the morphology contrast of the secondary electron image

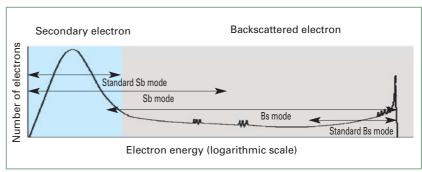
Bs mode (Mainly Backscattered electrons)

The Bs mode detects the backscattered electrons mixed with a variable fraction of the secondary electrons to show a mixture of the composition contrast of the backscattered electrons and the surface morphologies enhanced by the edge effect of the secondary electrons.

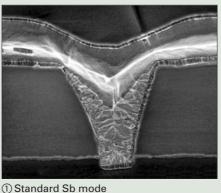
Figure 4: You can observe the contrast of composition difference between the tungsten and the aluminum layers, and the surface morphology on the aluminum layer.



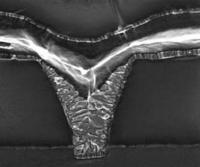
The new r-filter selectively detects secondary and backscattered electrons.



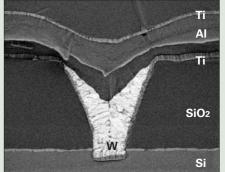
The energy ranges selected by the new-filter



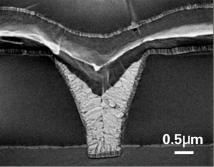












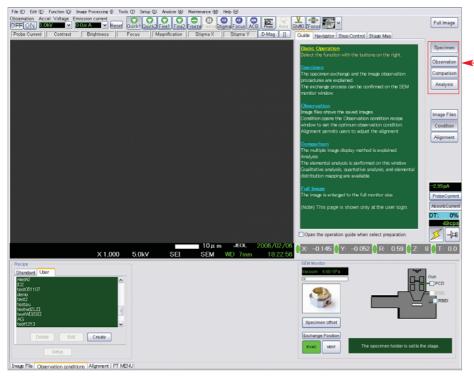
(4) Bs mode 1kV

Seamless Integration for Efficient Observation

New GUI for smooth operation—from specimen exchange, versatile imaging to analysis—

The JSM-7500F and JSM-7500FA incorporate the newly developed AIP signal-processor. Up to four live images can be displayed simultaneously. Up to four live images can be added and displayed. A series of operations —from specimen exchange, observation to report creation— can be made seamlessly. In addition, you can start the EDS analysis on the SEM image instantaneously.

Specimen preparation screen (Insert a specimen.)



Help display

Clicking on the Guide tab displays the method of operation you selected.

Purpose button

Clicking on specimen preparation displays this monitor screen. You can switch the monitor screen from observation to elemental analysis.

One-action specimen exchange

You can surely exchange a specimen simply by inserting the specimen exchange rod to the specimen chamber through the airlock chamber. You do not have to open the specimen chamber every time you exchange it, reducing specimen contamination.

Automatic specimen exchange airlock chamber

The automatic specimen exchange airlock chamber can be used with all specimen stages. A specimen holder is automatically attached to the specimen stage by placing the specimen holder in the chamber.

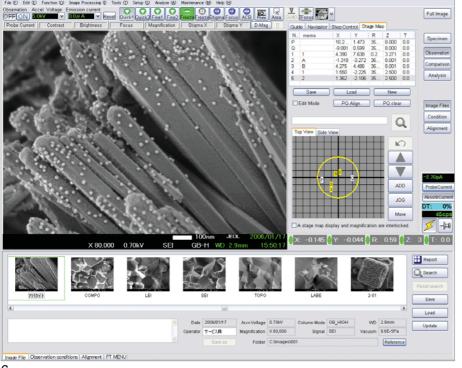
Specimen holder

When you select a specimen holder, the graphic display of the stage changes according to your selection. The safety mechanism for limiting the stage movement is also linked to the holder.

Operating conditions memory

You can select suitable operating conditions from your observation recipes.

Observation mode screen (All functions necessary for observation are displayed.)



High-definition live image display

A high-definition display system acquires an image with 1280×960 pixels for live image display. Bright, clear images appear on the monitor screen.

Automatic functions

Focusing, brightness and contrast adjustment, and astigmatism correction can be automated, enhancing observation efficiency.

Five-axis motor controlled stage

The eucentric specimen stage is motor controlled for all five axes.

Stage Map

Stage Map displays the location of the specimen holder in the graphic display. You can move the specimen stage to any stored location by clicking or dragging it on the graphic display.

Image saving

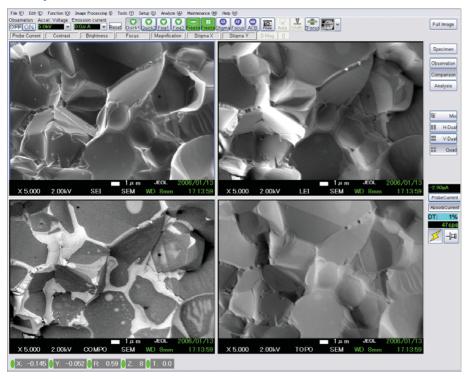
Clicking on the Photo icon acquires images. The index display shows the images you have saved. You can move back to the previously acquired location by selecting the thumbnail image and observe the image with the same conditions. When the image with EDS data is selected, the analysis results are displayed.

Report creation

You can create a report simply by selecting a thumbnail image and paste it on the layout sheet.

and Analysis

Comparison screen



Simultaneous acquisition of four different images

The comparison mode simultaneously displays four different live images from the followings: a) image obtained with the upper detector, b) image obtained with the lower detector, c) composition image formed by backscattered electrons, d) topographic image formed by backscattered electrons, d) STEM image.

Furthermore, four different images can be simultaneously acquired with high definition, at one-time scan. This is effective for reducing beam damage and specimen contamination. All images are high definition (1280×960 pixels).

SEI	SEI or BEI
(upper detector)	(lower detector)
BEI	BEI
(composition)	(topography)

Ceramic

Flexible specimen movement

The JSM-7500F and JSM-7500FA come with a five-axis motor controlled stage. This stage has further improved its stability against floor vibration.

The high sensitivity trackball enables you to move the specimen stage freely with your finger touch at any magnification.

The specimen stage control software is provided for saving the specimen stage coordinates, and for moving the specimen stage stepwise as well as continuously.





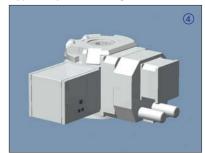
Type I specimen exchange chamber/ Type IA specimen stage



Type I specimen exchange chamber/ Type II specimen stage



Auto specimen exchange chamber/ Type IA specimen stage



Auto specimen exchange chamber/ Type **III** specimen stage

Stage	Type IA stage	Type II stage	Type Ⅲ stage
Exchange	X=70mm, Y=50mm	X=110mm, Y=80mm	X=140mm, Y=80mm
Type I airlock	1	3	
Max.6-inch	86mm ϕ cover	152.4mm ϕ cover	152.4mm ϕ cover
Type II airlock			
Max.4-inch×40mmH	86mm ϕ cover	100mm ϕ cover	_
Auto airlock	2		4
Max.8-inch	86mm ϕ cover	152.4mm ϕ cover	203.2mm ϕ cover

Coverage indicated above is achieved with X-Y and rotation.



Principal Specifications

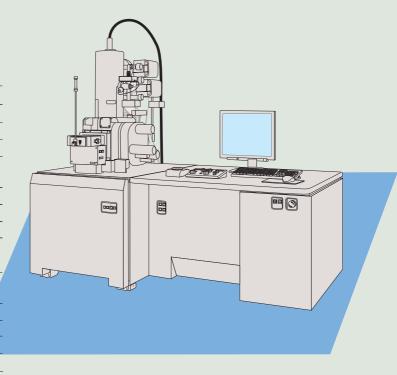
Resolution	1.0nm (15kV), 1.4nm (1kV)			
Magnification	×25 to ×1,000,000			
Accelerating voltage	0.1kV to 30kV			
Probe current	1pA to 2nA			
Aperture angle optimizing lens	Built-in			
Detectors	Upper detector, Lower detector			
Energy filter	New r-filter			
Gentle Beam	Built-in			
Digital image	1,280×960 pixe	els, 2,560×1,920) pixels,	
	5,120×3,840 pixels			
Specimen exchange chamber	One-action specimen exchange mechanism built-in			
Specimen stage	Eucentric, 5 axes motor control			
Туре	IA	II	Ш	
X-Y	70mm×50mm	110mm×80mm	140mm×80mm	
Tilt	−5 to +70°	−5 to +60°	−5 to +60°	
Rotation	360°	360°	360°	
WD	1.5mm to 25mm	1.5mm to 25mm	1.5mm to 25mm	
Evacuation system	Three SIPs, TMP, RP, Fore-line trap			
Eco design	During normal operation: 1.2kVA During the sleep mode: 1kVA During the evacuation system OFF: 0.76kVA			

CO₂ Emission

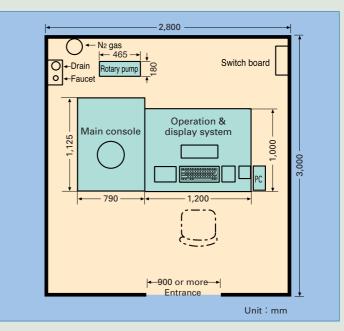
	CO ₂ /hour	CO ₂ /year
During normal operation	0.481kg	4,214kg
During the sleep mode	0.411kg	_
● During the evacuation system OFF (Ion pump ON)	0.286kg	_

Principal Options

- Retractable Backscattered Electron Detector
- In-lens Backscattered Electron Detector
- Energy Dispersive X-ray Spectrometer (EDS)
- Electron Back Scatter Diffraction (EBSD)
- Transmission Electron Detector
- Liquid Nitrogen Trap



Example of Installation Layout



*Specifications subject to change without notice.



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http://www.jeol.com/

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